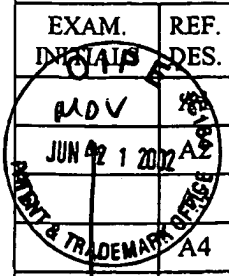


Form PTO-1449 (modified) List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)			ATTY. DKT. NO. 5119-08401 APPLICANT: Choi et al. FILING DATE: August 21, 2001		SERIAL NO. 09/934,248 GROUP: 3682		
U.S. PATENT DOCUMENTS							
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	A1	3,807,027	4/1974	Heisler			
	A2	3,807,029	4/1974	Troege			
		3,811,665	5/1974	Seelig			
	A4	4,062,600	12/1977	Wyse			
	A5	4,098,001	7/1978	Watson			
	A6	4,155,169	5/1979	Drake et al.			
	A7	4,202,107	5/1980	Watson			
	A8	4,267,212	5/1981	Sakawaki			
	A9	4,337,579	7/1982	De Fazio			
	A10	4,355,469	10/1982	Nevins et al.			
	A11	4,414,750	11/1983	De Fazio			
	A12	4,451,507	5/1984	Beltz et al.			
	A13	4,610,442	9/1986	Oku et al.			
	A14	4,694,703	11/1987	Routson			
	A15	4,731,155	3/1988	Napoli et al.			
	A16	4,763,886	8/1988	Takei			
	A17	4,929,083	5/1990	Brunner			
	A18	4,959,252	11/1990	Bonnebat et al.			
	A19	5,072,126	12/1991	Progler			
	A20	5,110,514	5/1992	Soane			
	A21	5,126,006	6/1992	Cronin et al.			
	A22	5,204,739	4/1993	Domenicali			
	A23	5,240,550	8/1993	Boehnke et al.			
	A24	5,348,616	9/1994	Hartman et al.			
	A25	5,392,123	2/1995	Marcus et al.			
	A26	5,425,964	6/1995	Southwell et al.			
	MDV	A27	5,452,090	9/1995	Progler et al.		

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List of Patents and Publications
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Disclosure Statement
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ATTY. DKT. NO. 5119-08401

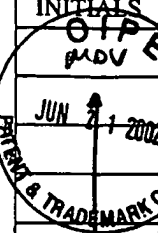
APPLICANT: Choi et al.

FILING DATE: August 21, 2001

SERIAL NO. 09/934,248

GROUP: 3682

U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	A28	5,480,047	1/1996	Tanigawa et al.			
	A29	5,512,131	4/1996	Kumar et al.			
	A30	5,515,167	5/1996	Ledger et al.			
	A31	5,545,367	10/1996	Bae et al.			
	A32	5,566,584	10/1996	Briganti et al.			
	A33	5,633,505	5/1997	Chung et al.			
	A34	5,724,145	3/1998	Kondo et al.			
	A35	5,753,014	5/1998	Van Rijn			
	A36	5,760,500	6/1998	Kondo et al.			
	A37	5,772,905	6/1998	Chou			
	A38	5,776,748	7/1998	Singhvi et al.			
	A39	5,779,799	7/1998	Davis			
	A40	5,802,914	9/1998	Fassler et al.			
	A41	5,877,036	3/1999	Kawai			
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	A44	5,900,160	5/1999	Whitesides et al.			
	A45	5,912,049	6/1999	Shirley			
	A46	5,942,871	8/1999	Lee			
	A47	5,948,470	9/1999	Harrison et al.			
	A48	5,952,127	9/1999	Yamanaka			
	A49	6,038,280	3/2000	Rossiger et al.			
	A50	6,039,897	3/2000	Lochhead et al.			
	A51	6,046,056	4/2000	Parce et al.			
	A52	6,051,345	4/2000	Huang			
	A53	6,074,827	6/2000	Nelson et al.			
	A54	6,091,485	7/2000	Li et al.			
	A55	6,128,085	10/2000	Buermann et al.			

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U.S. PATENT DOCUMENTS							
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
MOV	A56	6,143,412	11/2000	Schueller et al.	—	—	
MOV	A57	6,168,845	1/2001	Fontana, Jr. et al.	—	—	
MOV	A58	6,180,239	1/2001	Whitesides et al.	—	—	
MOV	A59	6,204,922	3/2001	Chalmers	—	—	
MOV	A60	6,334,960	1/2002	Wilson et al.	—	—	
FOREIGN PATENT DOCUMENTS							
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
MOV	A61	00/54107	9/2000	WO	—	—	
MOV	A62	01/33232	5/2001	WO	—	↑	
MOV	A63	01/33300	5/2001	WO	—	↑	
MOV	A64	244884	3/1987	EP	—	↑	
MOV	A65	733455	9/1996	EP	—	↑	NO
MOV	A66	2800476	7/1978	DE	—	↑	NO
MOV	A67	19648844	11/1999	DE	—	↓	NO
MOV	A68	1-196749	8/1989	JP	—	—	NO

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
MDV	A69	Stewart, D.; "A Platform with Six Degrees of Freedom", Proc. of Inst. Mech. Engrs., 1965, 180, 371-374.	
	A70	Paros, J.M.; Weisbord, L.; "How to Design Flexure Hinges", Machine Design, 1965, 151-156.	
	A71	Raibert, M.H.; Craig, J.J.; "Hybrid Position/Force Control of Manipulators", 1981, 102, 126-133.	
	A72	Hogan, Neville; "Impedance Control: An Approach to Manipulation", Journal of Dynamic Systems, Measurement and Control, 1985, 107, 1-7.	
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	A75	Slocum, Alexander; "Precision Machine Design: Macromachine Design Philosophy and its Applicability to the Design of Micromachines", Proc. of IEEE Micro Electro Mech. Systems Workshop, 1992, 37-42.	
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	A77	Arai, T.; Larssonneur, R.; Jaya, Y.M.; "Calibration and Basic Motion of a Micro Hand Module", Proc. of IECON, 1993, 1660-1665.	
	A78	Peng, Zhi-Xin; Adachi, N.; "Compliant Motion Control of Kinematically Redundant Manipulators", IEEE Transactions on Robotics and Automation, 1993, 9, 831-837.	
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	A84	Howell, L.L.; Midha, A.; "Loop-Closure Theory of the Analysis and Synthesis of Compliant Mechanisms", Journal of Mechanical Design, 1996, 118, 121-125.	
	A85	Haisma, J. et al.; "Mold-Assisted Nanolithography: A Process for Reliable Pattern Replication", Journal of Vacuum Science and Technology, 1996, 14, 4124-4128.	
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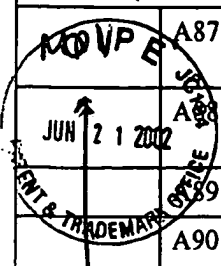
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	A87	Rong, L.; Guanghai, Z.; "Dynamics of Parallel Mechanism with Direct Compliance Control", 1997, 1753-1758.	
	A88	Mittal, Samir; Menq, Chia-Hsiang; "Precision Motion Control of Magnetic Suspension Actuator Using a Robust Nonlinear Compensation Scheme", IEEE/ASME Transactions on Mechatronics, 1997, 2, 268-280.	
	A89	Physik Instruments, Product Catalog for Micropositioning, 1997.	
	A90	Williams, Mark et al.; "Six Degree of Freedom Mag-Lev Stage Development", SPIE, 1997, 3051, 856-867.	
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	A97	Wang, W.; Loh, R.; Gu, E.; "Passive Compliance Versus Active Compliance in Robot-Based Automated Assembly Systems", Industrial Robot, 1998, 25, 48-57.	
	A98	Scheer, H.C. et al.; "Problems of Nanoimprinting Technique for Nanometer Scale Pattern Definition", Journal of Vacuum Science and Technology, 1998, 16, 3917-3921.	
	A99	Xia, Y.; Whitesides, George; "Soft Lithography", Annu. Rev. Mater. Sci., 1998, 28, 153-184.	
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	A101	Lee, Dong Sung et al.; "Ultra Precision Positioning System for Servo Motor-Piezo Actuator Using Dual Servo Loop and Digital Filter Implementation", ASPE, 1998, 18, 287-290.	
	A102	Wu, Wei et al.; "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography", 1998, Journal of Vacuum Science and Technology, 1998, 16, 3825-3829.	
	A103	Ohya, Y. et al.; "Development of 3-DOF Finger Module for Micro Manipulation", Proc. of IEEE, Intl. Conf. on Intelligent Robots and Systems, 1999, 894-899.	
	A104	Tanikawa, T. et al.; "Development of Small-Sized 3 DOF Finger Module in Micro Hand for Micro Manipulation", Proc. of IEEE, Intl. Conf. on Intelligent Robots and Systems, 1999, 876-881.	
WAV	A105	Colburn, M. et al.; "Step and Flash Imprint Lithography: New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, 3676, 379-389.	

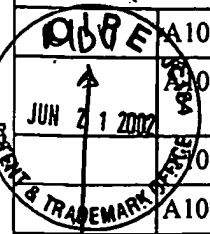
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	A106	Lucas Aerospace, Free-Flex Pivot Catalog, 1999	
	A107	Goldfarb, M.; Speich, J.E.; "A Well-Behaved Revolute Flexure Joint for Compliant Mechanism Design", Journal of Mech. Design, 1999, 121, 424-429.	
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	A109	Hexel Corporation, Tornado 2000 System Specifications, 1999, from www.hexel.com	
	A110	Physik Instruments, PI Online-Catalog, 1999, from www.physikinstrument.com	
	A111	Chou, Stephen; Zhuang, Lei; "Lithographically-induced Self Assembly of Periodic Micropillar Arrays", Journal of Vacuum Science and Technology, 1999, 17, 3197-3202.	
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	A114	Stix, Gary; "Getting More from Moore's", Scientific American, 2001, from www.scientificamerican.com	
	A115	Trilogy Systems, Linear Motors 310 Specification, 2001, from www.trilogysystems.com	
	A116	Choi, B.J. et al.; "Design of Orientation Stages for Step and Flash Imprint Lithography", Precision Engineering, 2001, 25, 192-199.	
	A117	PCT International Search Report for PCT/US 00/30041, dated 10/15/2001	
MSV	A118	PCT International Search Report for PCT/US 01/26049, dated 2/19/2002	

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Sheet

1

of

2

Application Number

09/934,248

Filing Date

08/21/2001

First Named Inventor

Choi et al.

Group Art Unit

3682

Examiner Name

Unassigned

Attorney Docket Number

PA19-09V07

U.S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

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		Application Number	09/934,248		
		Filing Date	08/21/2001		
		First Named Inventor	Choi et al.		
		Group Art Unit	3682		
		Examiner Name	Unassigned		
Sheet	2	of	2	Attorney Docket Number	PA19-09V07

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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
MDV	B18	LIN, "Multi-Layer Resist Systems", Introduction of Microlithography, American Chemical Society, 1983, pp. 287-350, IBM T.J. Watson Research Center, Yorktown Heights, New York 10598.	
MDV	B19	COWIE, "Polymers: Chemistry and Physics of Modern Materials", 1991, pp. 408-409, 2 nd Ed, Chapman and Hall, a division of Routledge, Chapman and Hall, Inc., 29 West 35 th Street, NY, NY 10001-2291.	
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MDV	B22	CHOU et al., "Imprint Lithography with Sub-10nm Feature Size and High Throughput", Microelectronic Engineering, 1997, pp. 237-240, vol. 35.	
MDV	B23	XIA et al., "Soft Lithography", Angew. Chem. Int. Ed., 1998, pp. 550-575, vol. 37.	

Examiner Signature	<i>M. Vung</i>	Date Considered	1/18/05
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Sheet

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Application Number	09/934,248
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Filing Date	08/21/2001
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First Named Inventor	Choi et al.
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Group Art Unit	1732
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Examiner Name	Vargot, Mathieu D.
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Attorney Docket Number	PA19-09V07
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FOREIGN PATENT DOCUMENTS

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Application Number	09/934,248
Filing Date	08/21/2001
First Named Inventor	Choi et al.
Group Art Unit	1732
Examiner Name	Vargot, Mathieu D
Attorney Docket Number	PA19-09V07

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Sheet	3	of	3	Attorney Docket Number	PA19-09V07
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Sheet 1 of 6

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Application Number	09/934,248
Filing Date	08/21/2001
First Named Inventor	Choi et al.
Group Art Unit	1732
Examiner Name	Vargot, Mathieu D.
Attorney Docket Number	PA19-09V07

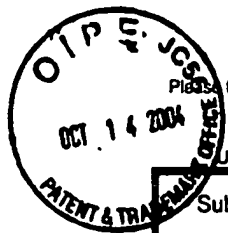
U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
MDV	C1	4,070,116		Frosch et al.	01-24-1978	
	C2	4,600,309		Fay	07-15-1986	
	C3	4,848,911		Uchida et al.	07-18-1989	
	C4	5,074,667		Miyatake	12-24-1991	
	C5	5,148,036		Matsugu et al.	09-15-1992	
	C6	5,148,037		Suda et al.	09-15-1992	
	C7	5,151,754		Ishibashi et al.	09-29-1992	
	C8	5,179,863		Uchida et al.	01-19-1993	
	C9	5,376,810		Hoenk et al.	12-27-1994	
	C10	5,424,549		Feldman	06-13-1995	
	C11	5,670,415		Rust	09-23-1997	
	C12	5,743,998		Park	04-28-1998	
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	C14	5,948,219		Rohner	09-07-1999	
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	C16	6,150,680		Eastman et al.	11-21-2000	
	C17	6,326,627	B1	Putvinski et al.	12-04-2001	
	C18	2002/0132482	A1	Chou	09-19-2002	
	C19	2002/0167117	A1	Chou	11-14-2002	
	C20	6,482,742	B1	Chou	11-19-2002	
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	C28	5,362,606		Hartney et al.	11-08-1994	
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	C33	5,439,766		Day et al.	08-08-1995	
	C34	5,431,777		Austin et al.	07-11-1995	
Examiner Signature	M. Vargot				Date Considered	1/18/05

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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Complete if Known

Application Number	09/934,248
Filing Date	08/21/2001
First Named Inventor	Choi et al.
Group Art Unit	1732
Examiner Name	Vargot, Mathieu D.
Attorney Docket Number	PA19-09V07

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
MDV	C35	5,422,295		Choi et al.	06-06-1995	
	C36	5,421,981		Leader et al.	06-06-1995	
	C37	5,417,802		Obeng	05-23-1995	
	C38	5,380,474		Rye et al.	01-10-1995	
	C39	5,374,454		Bickford et al.	12-20-1994	
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	C60	6,489,068	B1	Kye	12-03-2002	
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	C67	6,703,190	B2	Elian et al.	03-09-2004	
MDV	C68	6,730,256	B1	Bloomstein et al.	05-04-2004	
Examiner Signature		M. Vargot			Date Considered	1/19/05

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Sheet

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Complete if Known**Application Number**

09/934.248

Filing Date

08/21/2001

First Named Inventor

Choi et al.

Group Art Unit

1732

Examiner Name

Vargot, Mathieu D.

Attorney Docket Number

PA19-09V07

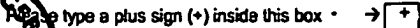
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Application Number	09/934,248
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Filing Date	08/21/2001
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First Named Inventor	Choi et al.
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Group Art Unit	1732
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Examiner Name	Vargot, Mathieu D.
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Attorney Docket Number PA19-09V07

FOREIGN PATENT DOCUMENTS

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Signature**

M. Vargst

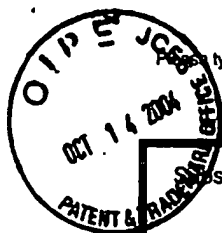
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				Filing Date	08/21/2001
				First Named Inventor	Choi et al.
				Group Art Unit	1732
				Examiner Name	Vargot, Mathieu D.
				Attorney Docket Number	PA19-09V07
Sheet	5	of	6		

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cita No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		T ²
MDV	C76	Abstract of Japanese Patent 63-138730		
MDV	C77	Abstract of Japanese Patent 55-88332		
MDV	C78	Abstract of Japanese Patent 57-7931		
MDV	C79	Abstract of Japanese Patent 02-92603.		
MDV	C80	Translation of Japanese Patent 02-92603.		
MDV	C81	Abstract of Japanese Patent 02-24848.		
MDV	C82	Translation of Japanese Patent 02-24848.		
MDV	C83	HEIDARI et al., "Nanoimprint Lithography at the 6 in. Wafer Scale," Journal of Vacuum Science Technology, Nov/Dec 2000, pp. 3557-3560, vol. B, no. 18(6)		
MDV	C84	NERAC.COM Retro Search, "Reduction of Dimension of Contact Holes", August 31, 2004		
MDV	C85	NERAC.COM Retro Search, "Trim Etching of Features Formed on an Organic Layer", September 2, 2004		
MDV	C86	NERAC.COM Retro Search, "Multi-Layer Resists", September 2, 2004		

Examiner Signature	M. Vargot	Date Considered	1/18/05
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known			
		Application Number	09/934,248		
		Filing Date	08/21/2001		
		First Named Inventor	Choi et al.		
		Group Art Unit	1732		
		Examiner Name	Vargot, Mathieu D.		
Sheet	6	of	6	Attorney Docket Number	PA19-09V07

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
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MDV	C87	HU et al., "Flourescence Probe Techniques (FPT) for Measuring the Relative Efficiencies of Free-Radical Photoinitiators", s0024-9297(97)01390-9; "Macromolecules" 1998, vol. 31, no.13, pp. 4107-4113, 1998 American Chemical Society. Published on Web 05/29/1998	
MDV	C88	FEYNMAN, Richard P., "There's Plenty of Room at the Bottom—An Invitation to Enter a New Field of Physics," 12 pp [online]Retreived 9/23/04 from URL:http://www.zyvex.com/nanotech/feynman.html.	
MDV	C89	CIBA SPECIALTY CHEMICALS BUSINESS LINE COATINGS, "What is UV Curing?", 45 pp [online]Retreived 9/24/04 from URL:http://www.cibasc.com/image.asp?id=4040.	

Examiner Signature	M. Vargot	Date Considered	1/18/05
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